

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

SUNG-KWON LEE

Application No.:

Filed:

For: **METHOD FOR FABRICATING
SEMICONDUCTOR DEVICE USING ARF
PHOTOLITHOGRAPHY CAPABLE OF
PROTECTING TAPERED PROFILE OF
HARD MASK**

Art Group:

Examiner:

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

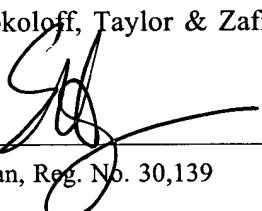
TRANSMITTAL OF FORMAL DRAWINGS

Sir:

Enclosed herewith for filing in the above-identified U.S. Patent Application are the formal drawings, 12 sheets including 20 Figures. Please charge any additional fees or credit any overpayment to Deposit Account No. 02-2666. A duplicate copy of the Fee Transmittal is enclosed for this purpose.

Respectfully submitted,
Blakely, Sokoloff, Taylor & Zafman LLP

Dated: 8/7/03


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